May 30, 2006



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: OHMI, et al.

led:

Serial No.:

10/566.241 January 30, 2006

Microwave Plasma Processing Method, Microwave Plasma Processing Apparatus, and It's Plasma Head

Art Unit:

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97 & 1.98

Mail Stop: DD

Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In the matter of the above-identified application, applicant(s) are submitting herewith copies of the documents listed in the attached Form(s) PTO/SB/08A and/or PTO/SB/08B for the Examiner's consideration.

This information disclosure statement is being submitted before the mailing date of a first office action.

To the extent that the documents listed on the attached form equivalent to Form(s) PTO/SB/08A and/or PTO/SB/08B are not in the English language, the requirement of 37 CFR 1.98(a)(3) for a concise explanation of the relevance is satisfied by an English language translation of the documents and the disclosure in the specification.

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this

paper, including excess claim fees, to Deposit Account No. 01-2135 (1113.45832X00), and please credit any excess fees to such deposit account.

Respectfully submitted,

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PTO/SB/08B (04-03)
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Substitute for for	m 1449/PTO		THE PROPERTY	Comp	elete If Known
				Application Number	10/566,241
INFORMATION DISCLOSURE			LOSURE	Filing Date	January 30, 2006
STATEMENT BY APPLICANT				First Named Inventor	Tadahiro OHMI
				Group Art Unit	
(use as many sheets as necessary)				Examiner Name	
Sheet	1	of	1	Attorney Docket Number	45832X00

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
/R.D./	_	Nikkel Microdevices 2001-1, To The Breakthrough Of Plasma CVD Technological LSI Production Revolution Which Does Not Use The Vacuum, page 3	L
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